



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Liu

Application No.: 10/634,964

Filed: 8/5/2003

Title: CHEMICAL MECHANICAL
PLANARIZATION COMPOSITIONS FOR
REDUCING EROSION IN SEMICONDUCTOR
WAFERS

Attorney Docket No.: 02039US

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Art Unit:
1765

Examiner:
Patricia A. George

RESPONSE

Dear Sir:

In response to the Office Action of July 6, 2005, having a statutory due date of October 6, 2005, please amend this application as follows: